

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Appln. Of: ASPAR et al  
For: A METHOD OF PRODUCING A THIN LAYER . . .  
DOCKET: BREV 12370CON 3

The Assistant Commissioner of Patents  
Washington, D.C. 20231

PRELIMINARY AMENDMENT

Dear Sir:

Applicants respectfully request that the following amendments be made to the above-identified application prior to examination.

IN THE CLAIMS:

Please cancel claims 1-12, without prejudice, and add new claims 13-20 reading as follows:

--13. A method for producing a thin film comprising:

providing a first substrate having a face surface;

introducing ions into the first substrate at the face surface, such that

microcavities are formed in the first substrate during or after introducing the ions, wherein the microcavities define a thin film layer extending from the first surface to the microcavities, and wherein the microcavities reside between solid bridges of the first substrate;

bonding a second substrate to the face surface of the first substrate; and

applying mechanical forces to fracture the solid bridges.

14. The method for producing a thin film according to claim 13, further comprising applying energy to the first substrate.

15. The method for producing a thin film according to claim 14, wherein applying energy comprises applying thermal energy.

16. The method for producing a thin film according to claim 14, wherein applying energy comprises applying energy after introducing ions.

17. A method for producing a thin film comprising:  
providing a first substrate having a face surface;  
introducing ions into the first substrate at the face surface and forming microcavities in the first substrate, wherein the microcavities define a thin film layer extending from the first surface to the microcavities, and wherein the microcavities reside between solid bridges of the first substrate;

bonding a second substrate to the face surface of the first substrate; and  
applying mechanical forces to fracture the solid bridges.

18. The method for producing a thin film according to claim 17, further comprising applying energy to the first substrate.

19. The method for producing a thin film according to claim 17, wherein applying energy comprises applying thermal energy.

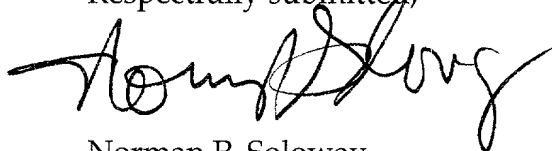
20. The method for producing a thin film according to claim 17, wherein applying energy comprises applying energy after introducing ions.--

REMARKS

New claims 13-20 are being presented to further scope the invention, and are believed allowable over the art, including specifically the art of record in the underlying parent applications.

The filing fees have been calculated based on the claims as amended. In the event there are any fee deficiencies or additional fees are payable, please charge them (or credit any overpayment) to our Deposit Account No. 08-1391.

Respectfully submitted,



Norman P. Soloway  
Attorney for Applicants  
Reg. No. 24,315

CERTIFICATE OF EXPRESS MAILING

"Express Mail" Mailing Label No. EL570816315US

Date of Deposit February 6, 2001

I hereby certify that this paper and the papers listed thereon are being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR 1.10 on the date indicated above and is addressed to Assistant Commissioner of Patents, Washington, DC 20231.

Signature of Person Mailing Kristine Stevens

Name of Person Mailing Kristine Stevens

cb